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Substitute for form 1449/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

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|------------------------|-------------------|
| Application Number | 10/666,147 |
| Filing Date | 18 September 2003 |
| First Named Inventor | Deb et al. |
| Art Unit | 2858 |
| Examiner Name | Not Yet Assigned |
| Attorney Docket Number | DB001039-001 |

Sheet 1 of 3

NON PATENT LITERATURE DOCUMENTS

| Examiner Initials* | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T ² |
|--------------------|-----------------------|---|----------------|
| HR | 1 | A. KOUROPENIS, J. BORENSTEIN, J. CONNELLY, R. ELLIOTT, P. WARD, and M. WEINBERG, "Performance of MEMS Inertial Sensors," Position Location and Navigation Symposium, pp. 1-8, April 1998. | |
| HR | 1 | R. LAL, P.R. APTE, N.K. BHAT, G. BOSE, S. CHANDRA, and D.K. SHARMA, "MEMS: Technology, Design, CAD and Applications," pp. 24-25, Jan. 2002. | |
| HR | 1 | S. CASS, "MEMS in Space," IEEE Spectrum, Vol. 38, Issue 7, pp. 56-61, July 2001. | |
| HR | 1 | D.C. HUTCHISON, K. OHARA, and A. TAKEDA, "Application of Second Generation Advanced Multimedia Display Processor (AMDP2) in a Digital Micro-Mirror Array Based HDTV," Int'l Conference on Consumer Electronics (ICCE) pp. 294-295, June 2001. | |
| HR | 1 | R.S. PAYNE, S. SHERMAN, S. LEWIS, and R.T. HOWE, "Surface Micromachining: From Vision to Reality to Vision," Proc. of International Solid State Circuits Conference, pp. 164-165, Feb. 1995. | |
| HR | 1 | R. OBOE, "Use of MEMS Based Accelerometers in Hard Disk Drives," Proc. of International Conference on Advanced Intelligent Mechatronics, Vol. 2, pp. 1142-1147, 2001. | |
| HR | 1 | A. HARTZELL and D. WOODILLA, "Reliability Methodology for Prediction of Micromachined Accelerometer Stiction," Proc. of Reliability Physics Symposium, pp. 202-205, March 1999. | |
| HR | 1 | N. DEB and R.D. (Shawn) BLANTON, "Analysis of Failure Sources in Surface-Micromachined MEMS," Proc. International Test Conference, pp. 739-749, Oct. 2000. | |
| HR | 1 | D. DE BRUYKER, A. COZMA, and R. PUERS, "A Combined Piezoresistive/Capacitive Pressure Sensor With Self-Test Function Based on Thermal Actuation," Proc. Solid State Sensors and Actuators, Vol. 2, pp. 1461-1464, 1997. | |
| HR | 1 | H.V. ALLEN, SC.C. TERRY, and D.W. DE BRUIN, "Self-Testable Accelerometer Systems," Proc. Micro Electro Mechanical Systems, pp. 113-115, 1989. | |

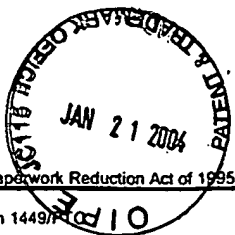
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| Examiner Signature | Helen Kwolek | Date Considered | 5/1/05 |
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PTO/SB/088 (08-03)

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| HZ | 1 | B. CHARLOT, S. MIR, F. PARRAIN, and B. COURTOIS, "Electrically Induced Stimuli for MEMS Self-Test," Proc. VLSI Test Symposium, pp. 210-215, Apr.-May 2001. | |
| HZ | 2 | R. ROSING, A. LECHNER, A. RICHARDSON, and A. DOREY, "Fault Simulation and Modelling of Microelectromechanical Systems," Computing and Control Engineering Journal, Vol. 11, Issue 5, pp. 242-250, Oct. 2000. | |
| HZ | 3 | A. KOLPEKWAR, R.D. BLANTON, and D. WOODILLA, "Failure Modes for Stiction in Surface-Micromachined MEMS," Proc. of International Test Conference, pp. 551-556, Oct. 1998. | |
| HZ | 4 | T. JIANG and R.D. BLANTON, "Particulate Failures for Surface-Micromachined MEMS," Proc. of International Test Conference, pp. 329-337, Sept. 1999. | |
| HZ | 5 | H. LUO, G.K. FEDDER, and L.R. CARLEY, "A 1 mG CMOS-MEMS Accelerometer," Proc. of Micro Electro Mechanical Systems, PP. 502-507, Jan. 2000. | |
| HZ | 6 | W.C. TANG, T.-C.H. NGUYEN, M.W. JUDY, and R.T. HOWE, "Electrostatic Comb Drive of Lateral Polysilicon Resonators," Sensors and Actuators A, Vol. 21, Nos. 1-3, pp. 328-331, Feb. 1990. | |
| HZ | 7 | J. XUESONG, J.I. SEEGER, M. KRAFT, and B.E. BOSER, "A Monolithic Surface Micromachined Z-axis Gyroscope with Digital Output," Symposium on VLSI Circuits, pp. 16-19, 2000. | |
| HZ | 8 | N. DEB and R.D. BLANTON, "High-Level Fault Modeling in Surface-Micromachined MEMS," Proc. of Design, Test, Integration, and Packaging of MEMS/MOEMS, pp. 228-235, May 2000. | |
| HZ | 9 | J. WU, G.K. FEDDER, and L.R. CARLEY, "A Low-Noise Low-Offset Chopper-Stabilized Capacitive-readout Amplifier for CMOS MEMS Accelerometers," Proc. of International Solid State Circuits Conference, pp. 428-429, Feb. 2002. | |
| HZ | 10 | O. TABATA, K. TERASOMA, N. AGAWA, and K. YAMAMOTO, "Moving Mask LIGA (M/sup 2/LIGA) Process for Control of Side Wall Inclination," Proc. of Micro Electro Mechanical Systems Conference, pp. 252-256, Jan. 1999. | |

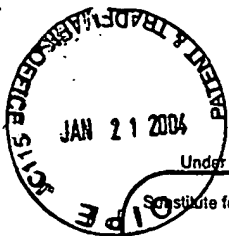
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| Examiner Signature | <i>Helen Kwik</i> | Date Considered | <i>5/5/05</i> |
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| HK | | S.V. IYER, H. LAKDAWALA, G.K. FEDDER, and T. MUKHERJEE, "Macromodeling Temperature-Dependent Curl in CMOS Micromachined Beams," Proc. of Modeling and Simulation of Microsystems Conference, pp. 88-91, March 2001. | |
| HK | | Q. JING, H. LUO, T. MUKHERJEE, L.R. CARLEY, and G.K. FEDDER, "CMOS Micromechanical Bandpass Filter Design Using a Hierarchical MEMS Circuit Library," Proc. of Micro Electro Mechanical Systems Conference, pp. 187-192, Jan. 2000. | |
| HK | | D.A. KOESTER, R. MAHADEVAN, and K.W. MARKUS, MUMPS Introduction and Design Rules, MCNC MEMS Technology Applications Center, 3021 Cornwallis Road Research Triangle Park, NC, Oct. 1994. | |
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| Examiner Signature | Helen Kwok | Date Considered | 5/5/05 |
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